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PPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/026,419	12/26/2001	Kenji Kawano	04329.2718	2486
75	590 03/29/2004		EXAMINER	
Finnegan, Henderson, Farabow,			CHACKO DAVIS, DABORAH	
Garrett & Dunner, L.L.P. 1300 I Street, N.W.			ART UNIT	PAPER NUMBER
Washington, DC 20005-3315			1756	

DATE MAILED: 03/29/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

*	Application No.	Applicant(s)			
	10/026,419	KAWANO ET AL.			
Office Action Summary	Examiner	Art Unit			
	Daborah Chacko-Davis	1756			
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address			
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.1: after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period of Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be time within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	nely filed s will be considered timely. the mailing date of this communication. D (35 U.S.C. § 133).			
Status					
1) Responsive to communication(s) filed on 16 D	ecember 2003.				
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Disposition of Claims					
 4) Claim(s) 1-85 is/are pending in the application 4a) Of the above claim(s) 15-85 is/are withdray 5) Claim(s) is/are allowed. 6) Claim(s) 1-14 is/are rejected. 7) Claim(s) is/are objected to. 8) Claim(s) are subject to restriction and/or 	vn from consideration.				
Application Papers					
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) acc Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Example 11.	epted or b) objected to by the drawing(s) be held in abeyance. Se tion is required if the drawing(s) is ob	e 37 CFR 1.85(a). jected to. See 37 CFR 1.121(d).			
Priority under 35 U.S.C. § 119					
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the priority application from the International Burea * See the attached detailed Office action for a list	ts have been received. ts have been received in Applicat rity documents have been receive u (PCT Rule 17.2(a)).	ion No ed in this National Stage			
Attachment(s) 1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date 12/2001.	4) Interview Summary Paper No(s)/Mail D 5) Notice of Informal 6				

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DETAILED ACTION

Election/Restrictions

1. Applicant's election without traverse of Group I, claims 1-14, in Paper No. is acknowledged.

Claim Rejections - 35 USC § 103

- 2. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 3. Claims 1-7, are rejected under 35 U.S.C. 103(a) as being unpatentable over U.
- S. Patent No. 6,644,964 (Shirakawa et al) in view of U. S. Patent No. 5,434,644 (Kitano et al).

Shirakawa, in col 1, lines 45-55, in col 2, lines 47-52, in col 4, lines 47-53, in col 9, lines 29-54, in col 12, lines 54-67, and in figures 8A, and 8B, discloses a heating apparatus comprising a chamber (reference 440), a heating plate for heating a substrate, wherein the heating plate includes a support surface to support the film coated substrate (reference W); a partition member (absorption plate, second plate portion, reference 221) that has a plurality of openings (pores) is positioned facing the support surface of the heating plate, and a supply port that supplies gas (nitrogen) to a lower portion through the openings in the second plate, wherein the gas stream passes through the area above and below the wafer surface (while being heated) and exhausts (the gas stream, and air within the chamber) through the exhaust port (reference 243)

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(claims 1, 5-6). Shirakawa, in col 2, lines 46-54, discloses that the partition member (plate) is detachably disposed in the apparatus (claim 2). Shirakawa, in col 9, lines 15-36, discloses that the second plate portion is porous (has openings) and comprise ceramic materials (claims 3, and 7). Shirakawa, in col 13, lines 5-7, discloses that the openings of the plate portions are within 0.3mm (claim 4).

The difference between the claims and Shirakawa is that Shirakawa does not disclose that the gas stream emanating from the partition member (adsorption plate, plate portion) discharges the substances evaporated from the film (along with the gas) through the exhaust port.

Kitano, in Kitano, in col 2, lines 43-52, in col 4, lines 28-40, and in col 5, lines 65-68, and in col 6, lines 1-2, discloses the use of a filter unit (partition member) in a processing station, wherein the filter unit absorbs the unwanted substances (such as alkali) and exhausts the substances through the outlets and prevents it from reaching the film surface.

Therefore, it would be obvious to a skilled artisan to modify Shirakawa by employing the filter unit suggested by Kitano because Kitano, in col 5, lines 60-64, discloses that employing such filters enables the developments of film patterns with high accuracy.

Allowable Subject Matter

4. Claims 8-14, are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

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Conclusion

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Daborah Chacko-Davis whose telephone number is (571) 272-1380. The examiner can normally be reached on M-F 9:30 - 6:00. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Mark F Huff can be reached on (571) 272-1385. The fax phone number for the organization where this application or proceeding is assigned is (703) 872-9306.

dcd

March 18, 2004.

MARK F. HUFF SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 1700